

Electrical Characterization of Rollers & Belts for High Speed Electrophotography

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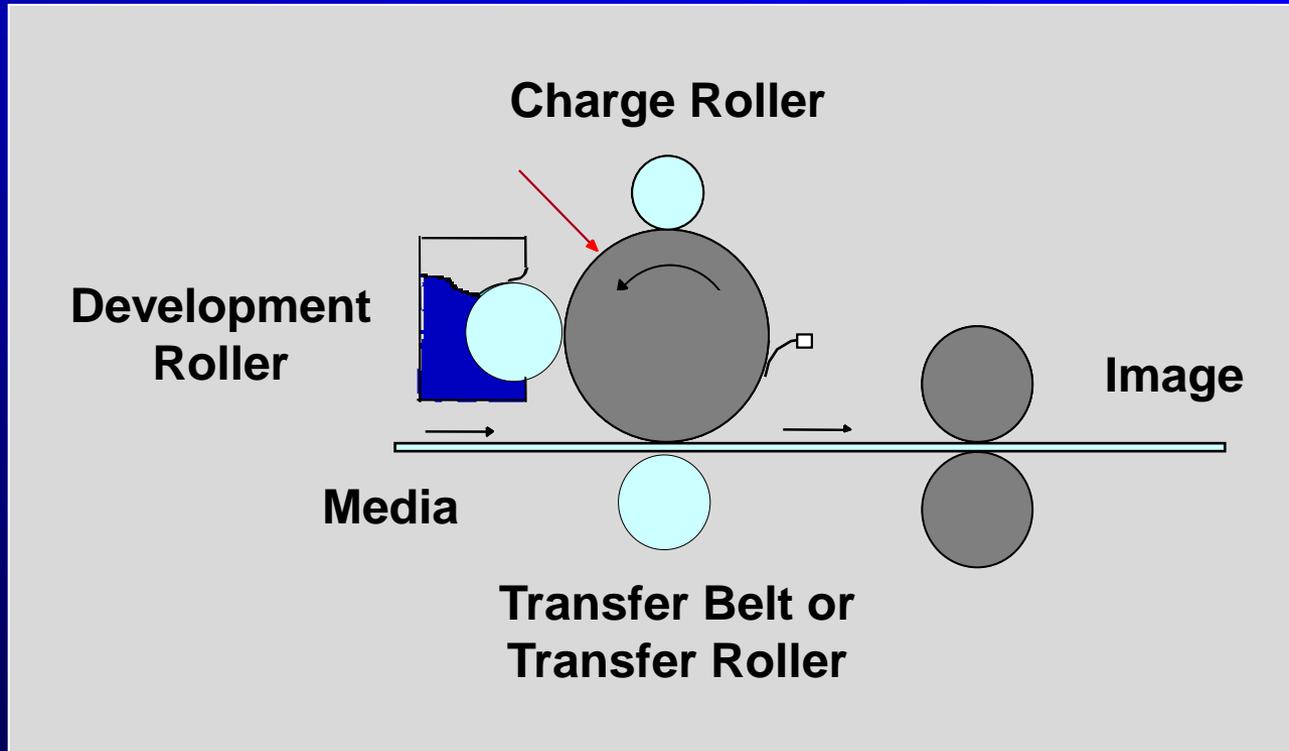
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Outline

- **What characterization method – measurement of dielectric relaxation**
- **Why – correlates with process fundamentals**
- **Traditional resistance measurement method – what's wrong**
- **ECD method – what's right**
- **Analysis & Experimental Results**

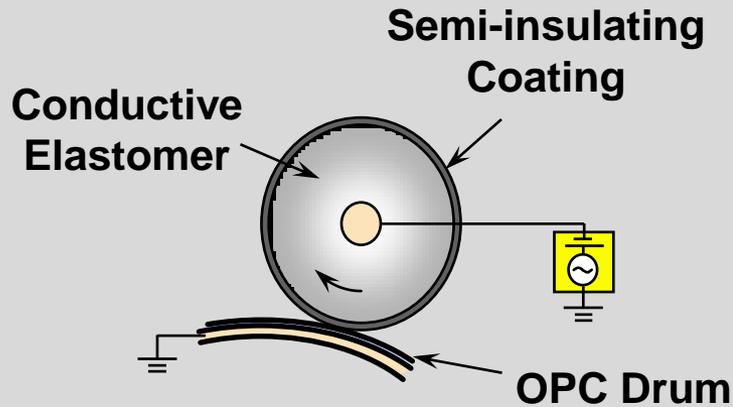
Dielectric Relaxation of Rollers & Belts is Critical to the Performance of Several EP Processes



Characterization of dielectric relaxation is the key!

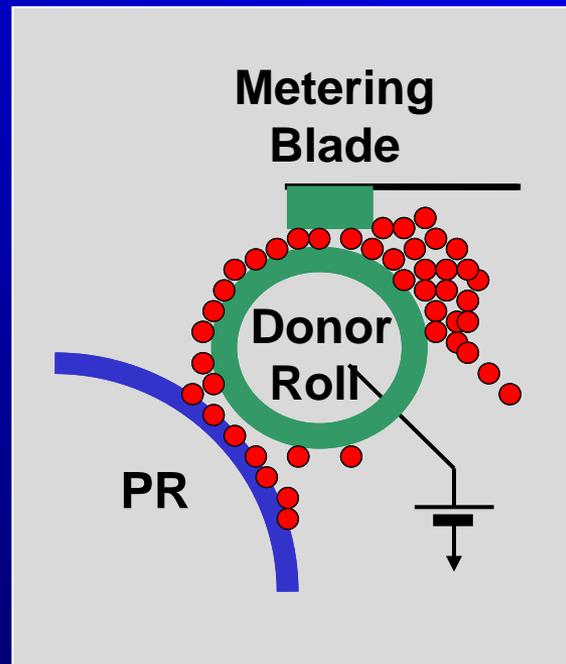
Why Dielectric Relaxation is Important?

Charging

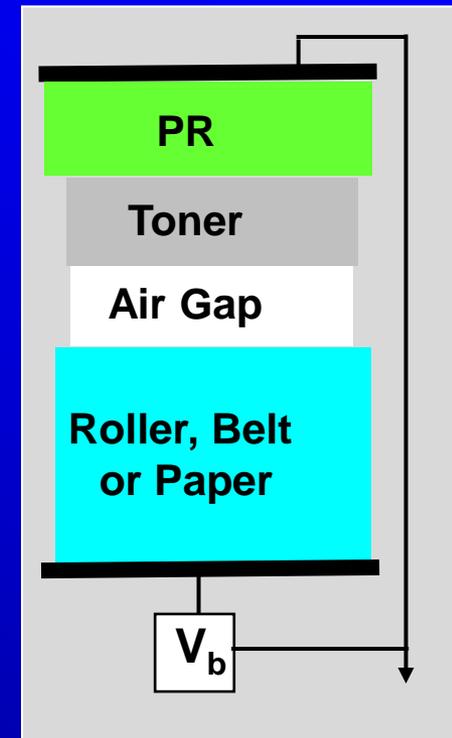


**Need to understand
the process physics**

Development



Transfer Media

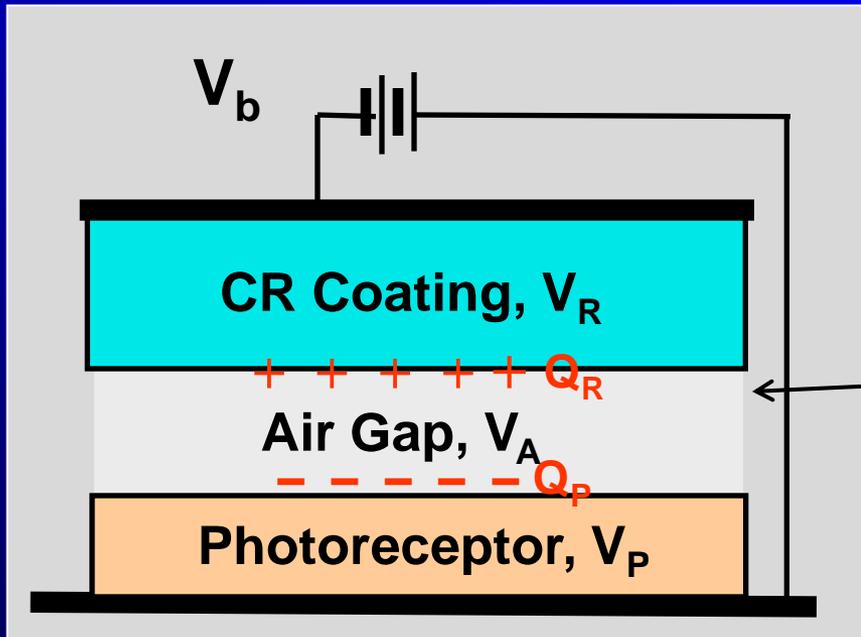


QEA Research & Publications

Year	Conference	Subject
1999	JHC	ECD method for semi-insulators
1999	NIP15	Modeling of electrostatic transfer
2000	NIP16	Transfer media
2001	NIP17	Corona charging current
2002	ICIS	Charge mobility measurement
2004	NIP20	Transfer of color images
2005	JHC	Semi-insulating devices
2005	NIP21	Roller charging of photoreceptor
2006	ICIS	Media non-uniformity issues
2006	NIP22	Counter charge in development rollers
2008	PPIC	Aging of donor rolls
2008	NIP24	Characterization for high speed EP



Dielectric Relaxation in CR Charging



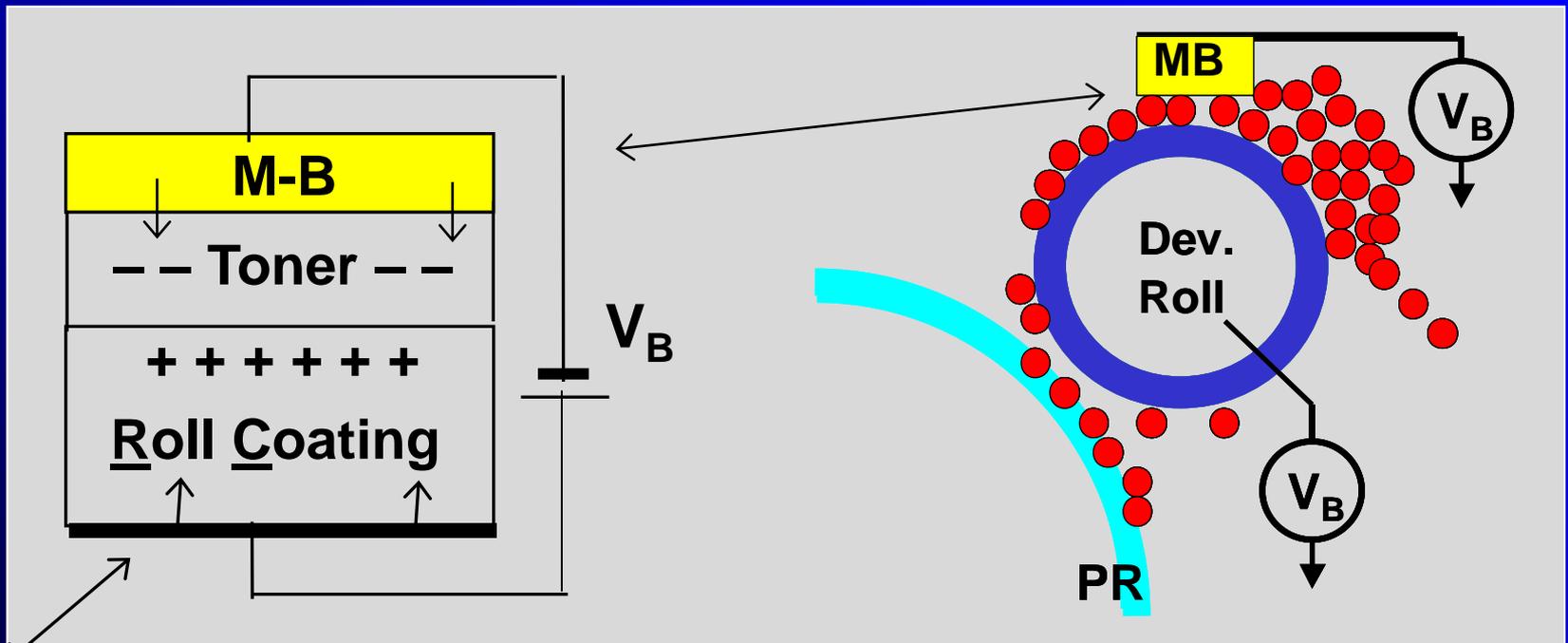
A qualitative description:

- Counter-charge Q_R on Roll
- Air-gap voltage, $V_A \downarrow$
- $V_A <$ Paschen threshold
- PR charging stops
- To continue charging, Q_R must be neutralized to $\downarrow V_R$ and $\uparrow V_A$
- *Dielectric relaxation* in roll coating important for high charging efficiency

- Roll coating voltage, $V_R \downarrow$
- Air gap voltage, $V_A \uparrow$
- $V_A >$ Paschen threshold
- PR surface charged, Q_P

Toner Charging in Single Component Development

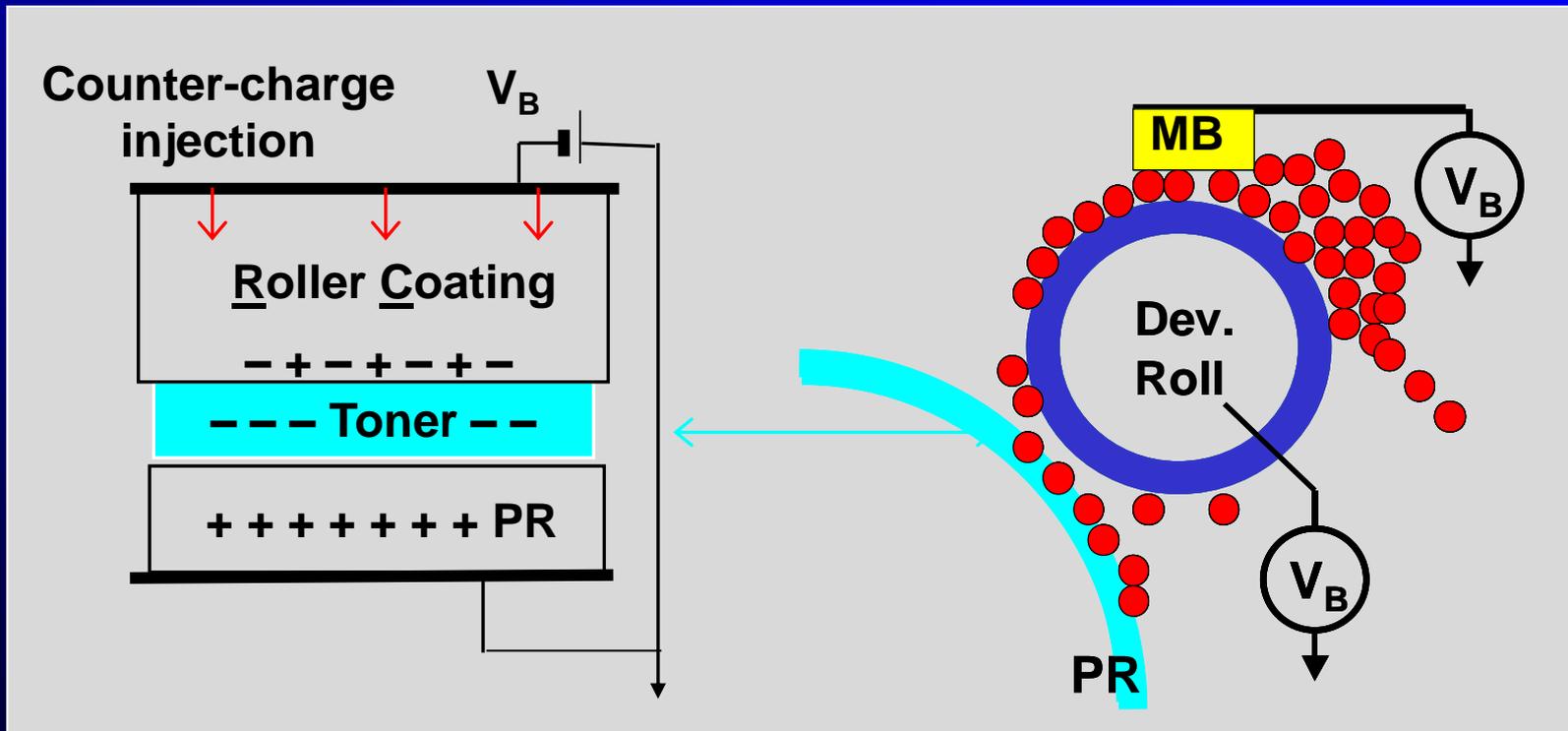
- Donor Roll = Conductive Core + Semi-ins. Overcoat
- Toner Charging (-) at Metering Blade (M-B)



- Counter-charge (+) injection from V_B
- V_{RC} decays, dielectric relaxation of roller coating

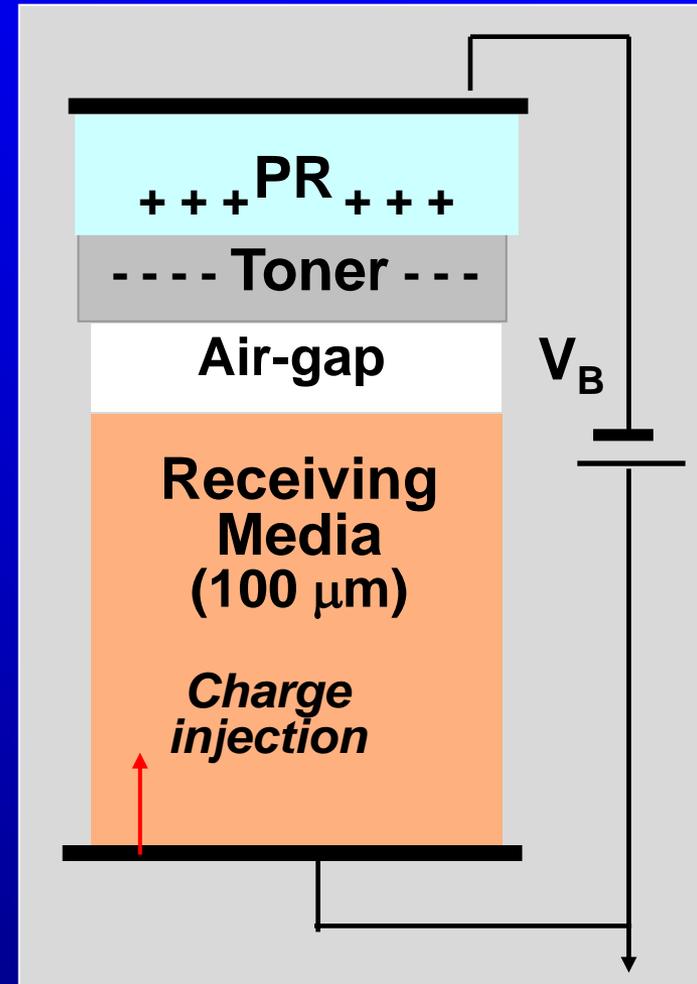
Toner Deposition in Single Component Development

- Toner Deposition on Photoreceptor (PR)
- Counter-charge (-) injection from V_B to Coating
- Dielectric Relaxation of Roll Coating layer



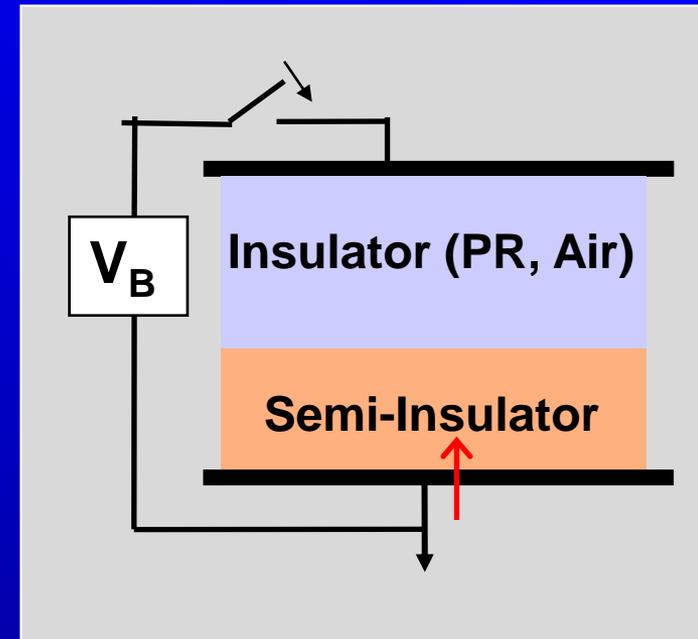
Electrostatic Transfer of Developed Toner

- Bias voltage applied to multiple layers
- V_B reverses field direction in toner layer
- Receiving media (Paper, Belt),
(semi-insulator) much thicker than other layers
- *Dielectric Relaxation* in receiver
 - Shifts most of V_B to toner layer
 - Enables efficient transfer
 - without very high bias voltages
 - occurs by charge injection

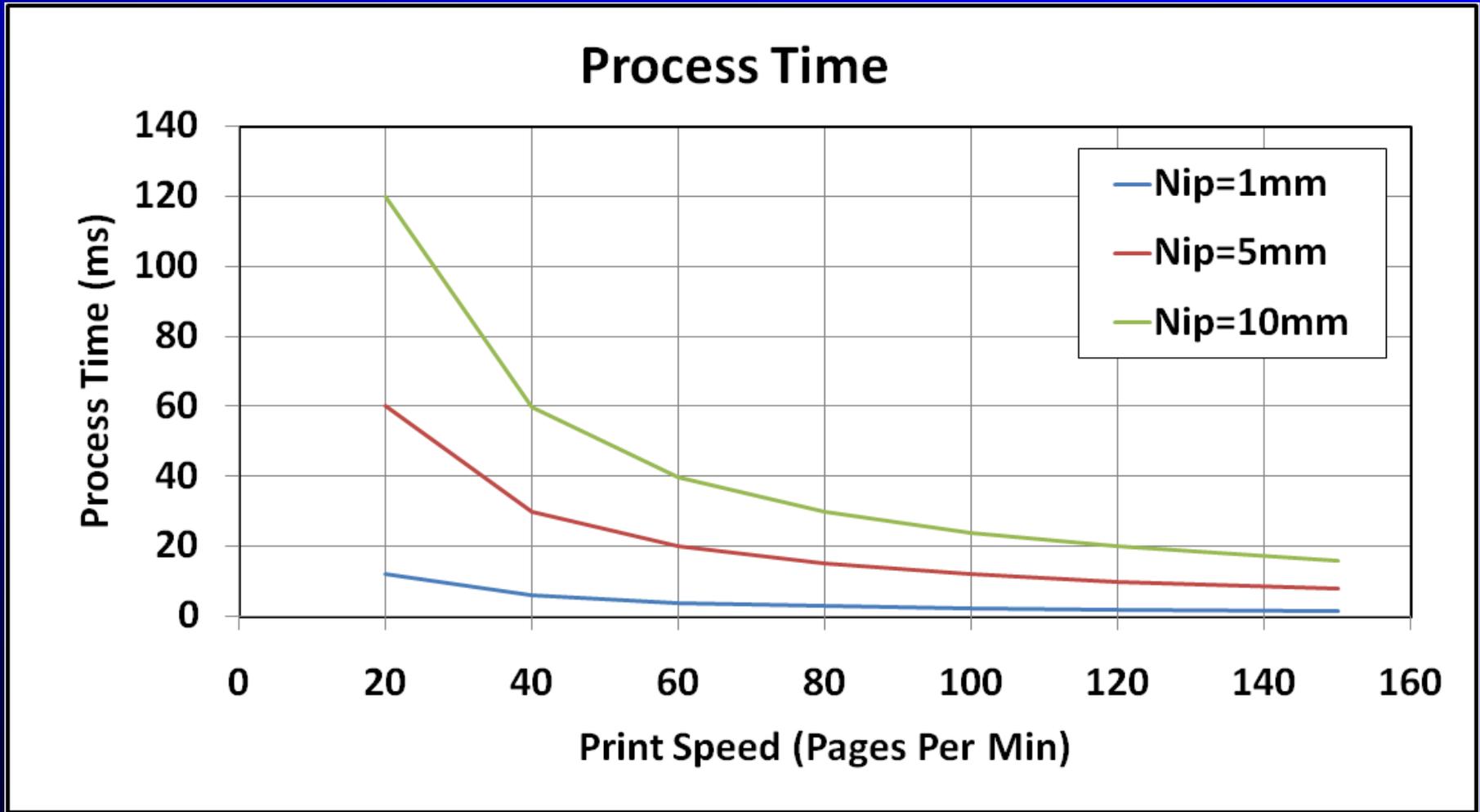


Common Configuration & Implications on Characterization Method

- V_B applied to insulator & semi-insulator in series
- Voltage across semi-insulator decays with time → *Dielectric Relaxation*
- Low intrinsic charge density
- Need charge injection
- Performance of process closely related to efficiency of dielectric relaxation, charge injection and transport
- Due to the complexity in the charge transport processes in dielectric relaxation – **best characterize by a test method that simulates actual device!**

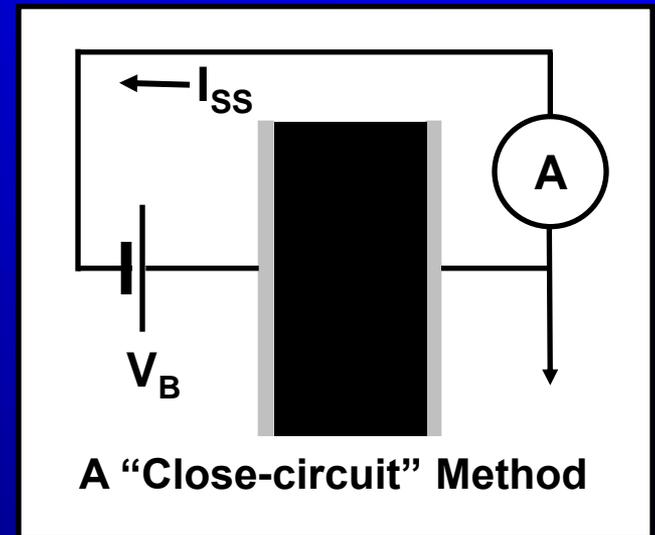
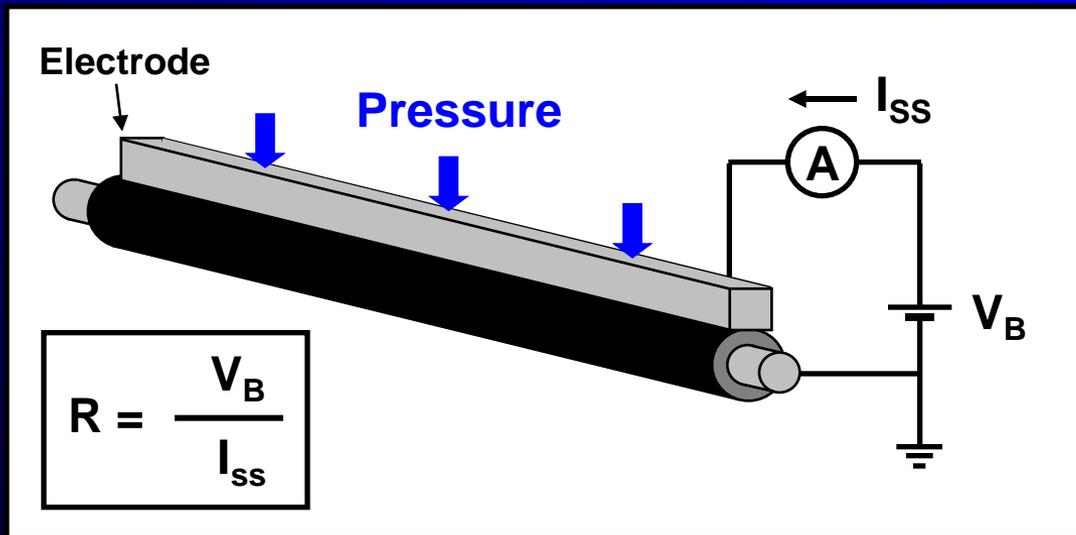


Process Time



Conventional Roller & Belt Characterization Method

- DC bias voltage is applied between an electrode in contact with the charge roller and the roller shaft. The current flow through the roller I_{ss} is measured, typically at “steady state”.
- The roller resistance is the ratio of the applied V_B to the measured I_{ss} .



Limitations of Conventional Resistance Method

- **Most serious is that the underlying physics is not consistent with the process physics:**
 - Ohmic relaxation model does not apply
 - Semi-insulator to electrode contact is non-ohmic
 - Test configuration does not simulate process configuration
 - no way to duplicate charge transport physics crucial to process performance (e.g., electric field dependence)
 - Measurement time scale is wrong
- **Practical issues:**
 - Contact pressure dependence
 - No mapping capability
- **Results do not reliably or consistently predict performance**

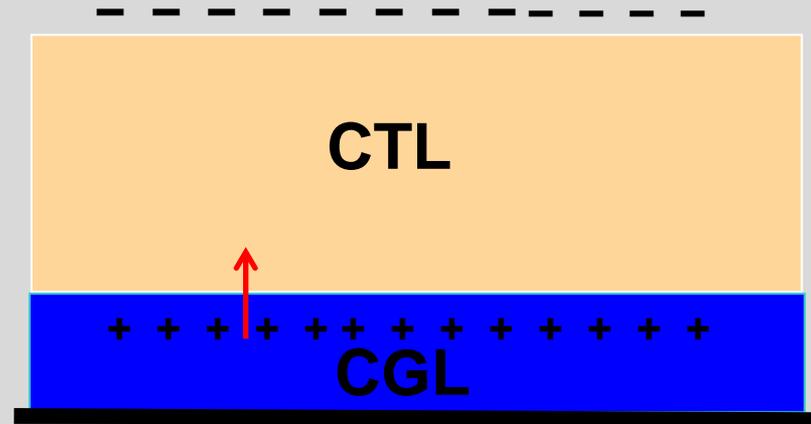
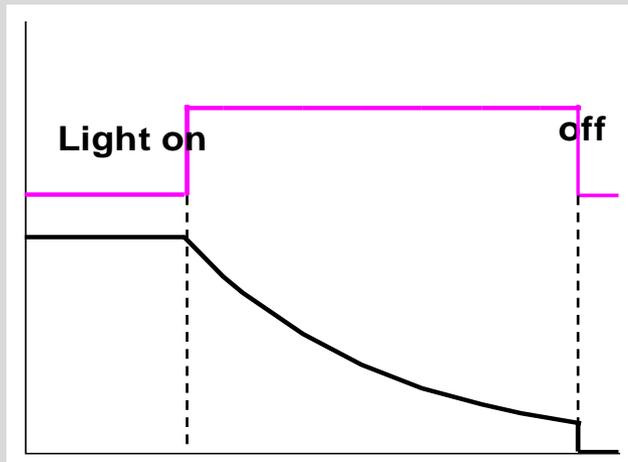


Ohmic vs Non-Ohmic Contact

- “Ohmic” contacts:
Supply charge to maintain $q = q_i$ (intrinsic charge density) in sample
Current density: $J = \sigma E_o = \mu q_i E_o$ (E_o = applied field)
- “**Non-Ohmic**” contacts:
Supply more or less charge (injection)
Charge density $q(x, t) \neq q_i$; $E(x, t) \neq E_o$; $J \neq \sigma E$
- **Semi-insulating devices are typically Non-ohmic. Injection at interface is key to the relaxation process.**
- **Conductivity, σ : not a good figure of merit!**

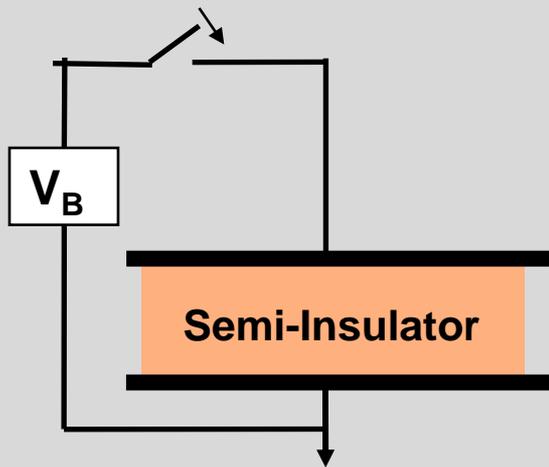
An Example of the Role of Injection – Photo-induced Discharge in Photoreceptor

- In the dark: an insulator with high resistivity with long dielectric relaxation time τ
- Exposed to light: charges photo-generated in CGL; **charge injection** into CTL \rightarrow Voltage decreases \rightarrow Photo-induced Dielectric Relaxation

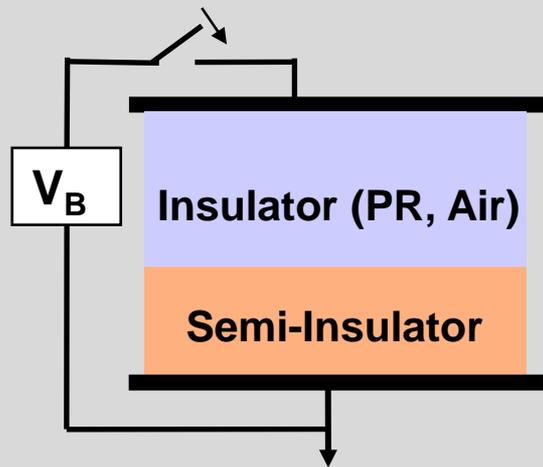


“Open-Circuit” Method is Preferred to Simulate Actual Device

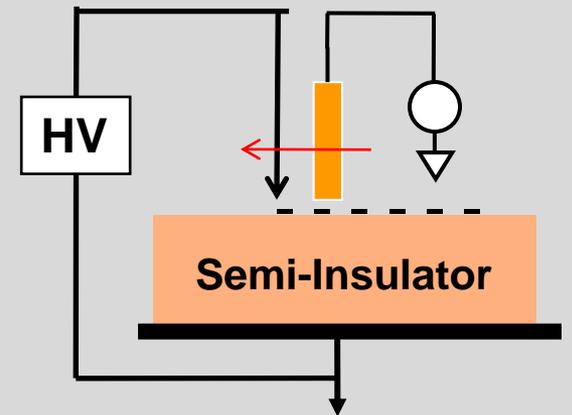
Testing Semi-insulator
In Closed Circuit



Semi-insulator
in Open Circuit



Testing Semi-insulator
In Open Circuit



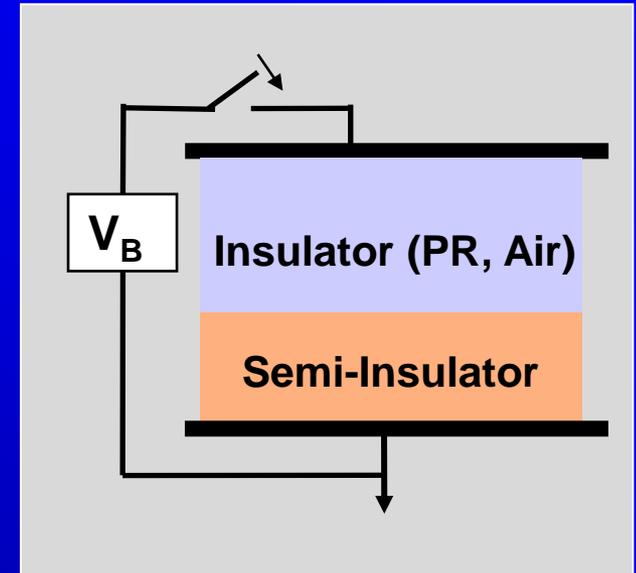
Traditional Resistance
Measurement

Device Configuration

Preferred ECD Method

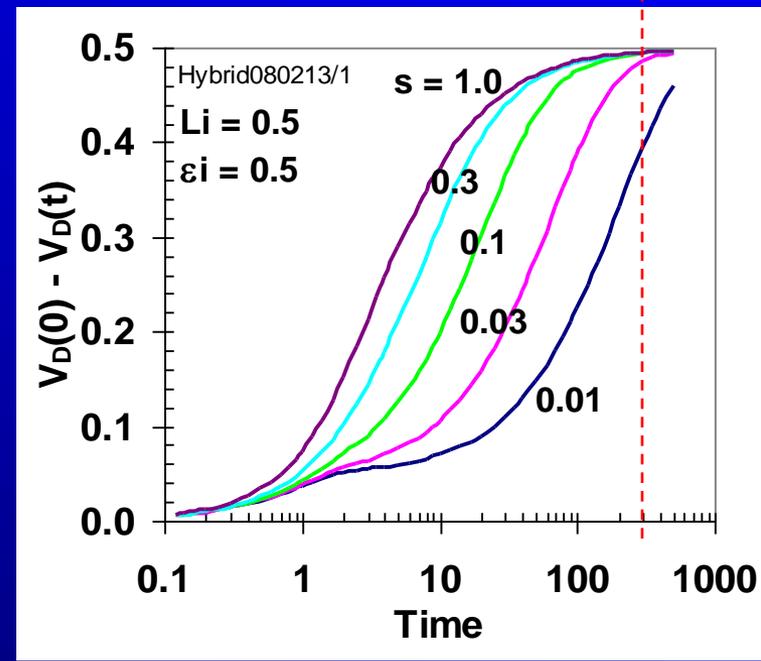
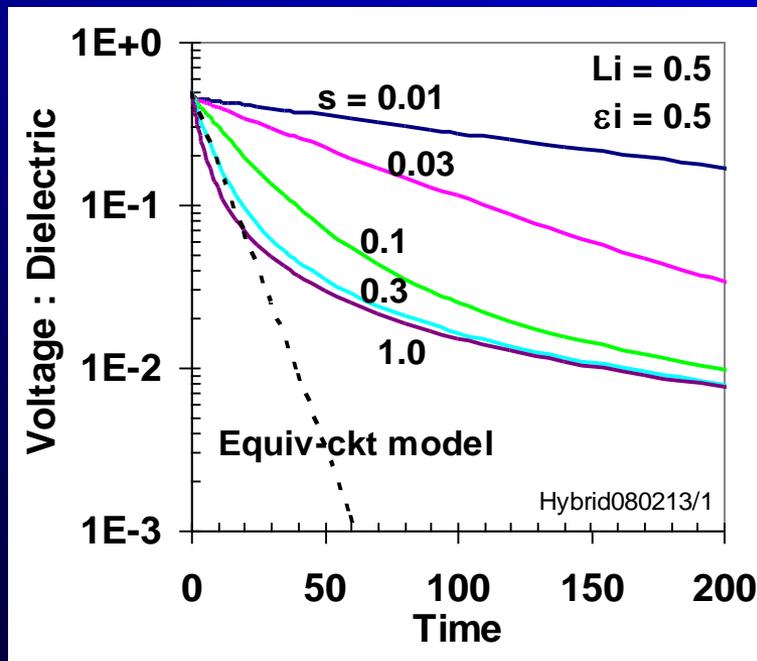
Charge Transport Model of Dielectric Relaxation (1)

- Samples characterized by:
 - Charge densities: $q_p(x,t)$, $q_n(x,t)$
 - Charge mobility: μ_p , μ_n
- Charge Continuity:
$$\partial q(y, t)/\partial t = - \partial(\mu q E)/\partial y$$
- Boundary conditions:
 - Injection current at $y = 0$
 $J(0, t) = sE(0, t)$, $s = \text{Injection strength}$
 - Interface charge: $Q_L = \epsilon_I E_I - \epsilon_D E_D(L)$
(Gauss' theorem)
 - Bias $V_B = V_D + V_I$ (constant in time)
- Solved by Numerical iterations



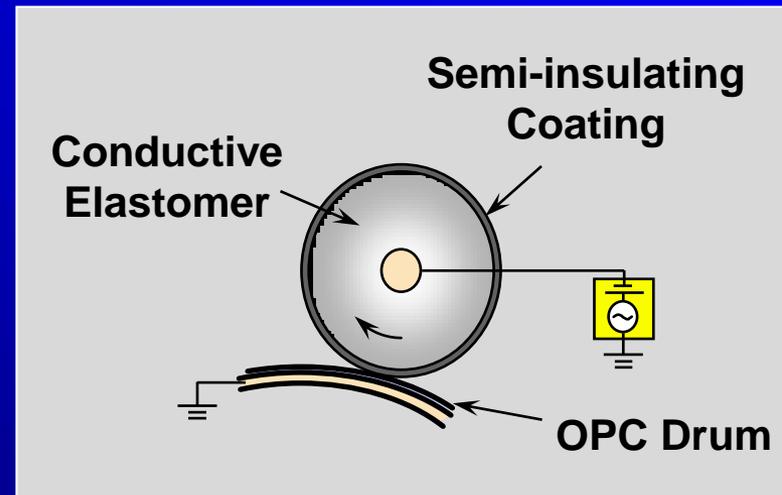
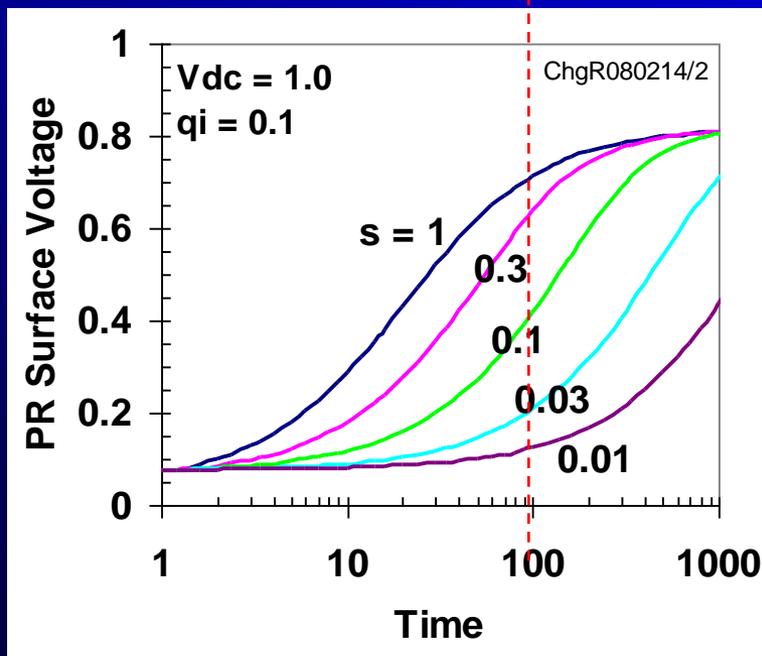
Charge Transport Model of Dielectric Relaxation (2)

- Voltage $V_D(t)$ across semi-insulator (dielectric) depends strongly on injection strength
- Voltage decay: $V_D(0) - V_D(t)$: significant effect of s in time $t \approx 10$ to $100 t_o$, ($t_o = L^2/\mu V_B$)



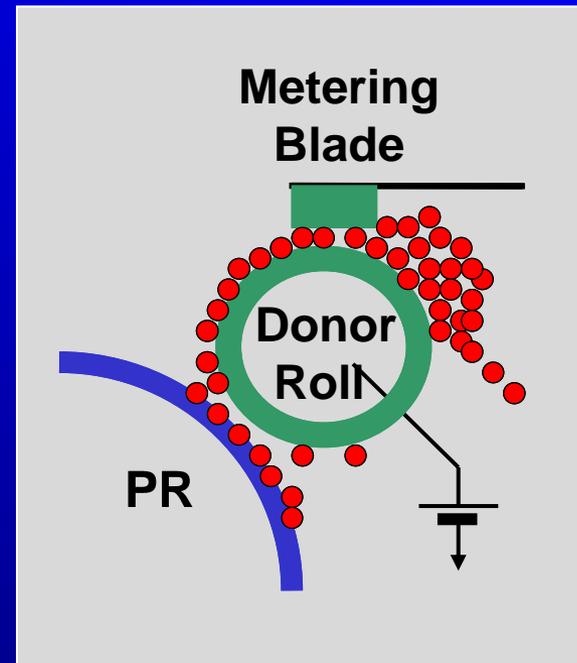
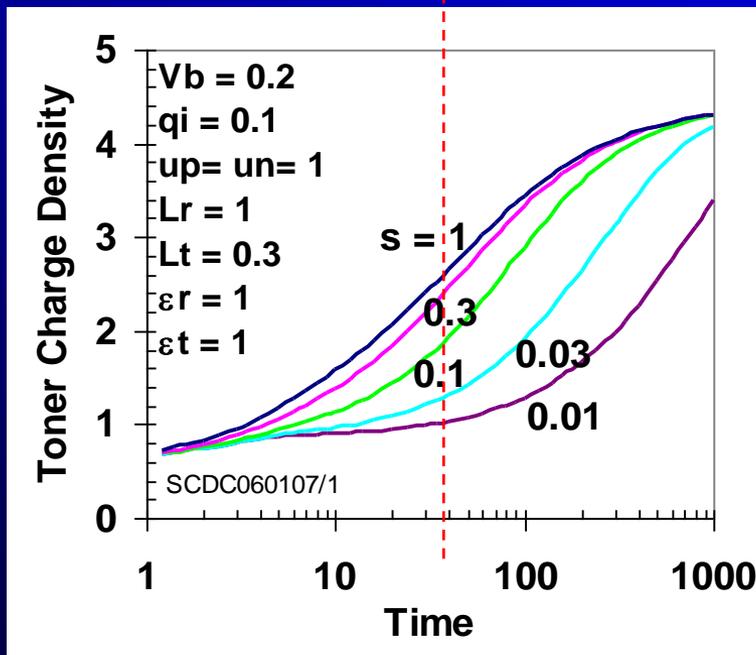
Roller Charging of Photoreceptor

- Photoreceptor surface voltage increases with time
- Significant effect of charge injection strength in time $t \approx 100 t_0$



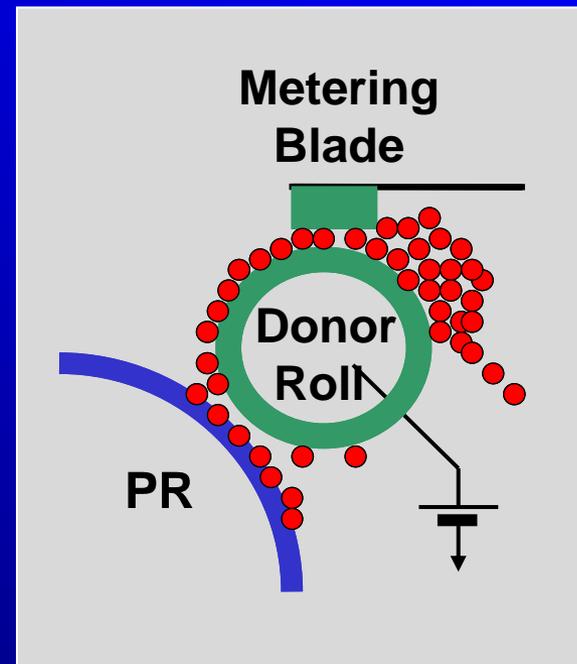
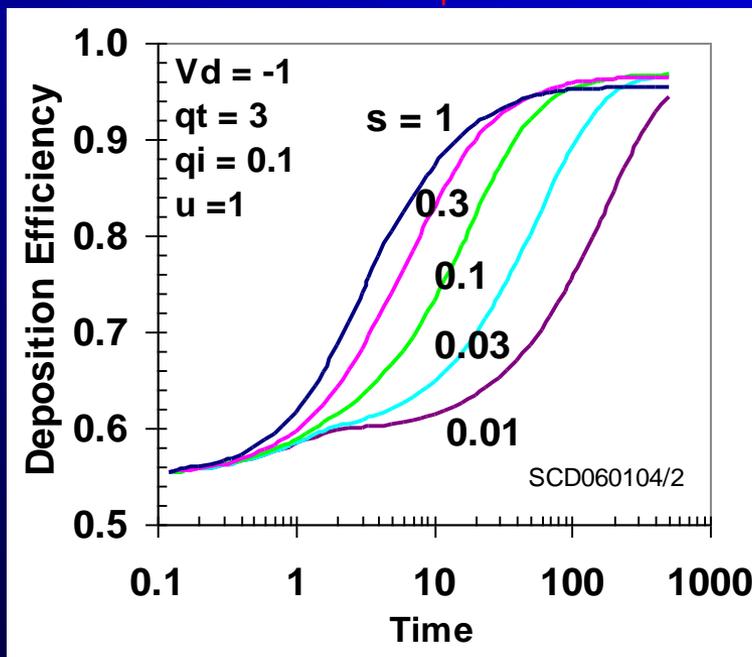
Toner Charging in Single Component Development

- Toner Charging (-) at Metering Blade (MB)
- Counter-charge (+) *injection* into Roll Coating
- Dependence on *injection strength* s in $t \approx 100 t_0$



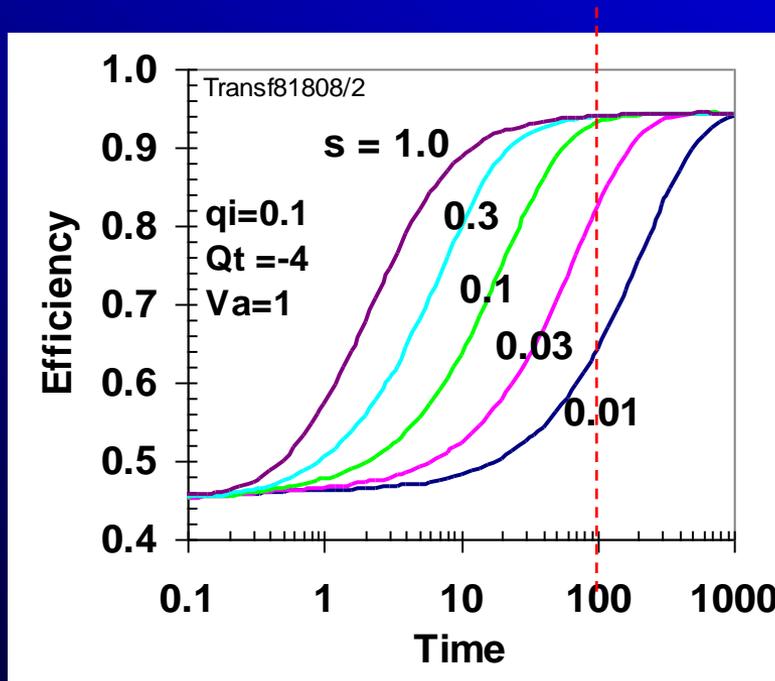
Toner Deposition in Single Component Development

- Toner deposition (–) on photoreceptor PR
- Counter-charge (–) *injection* into Roll Coating
- Dependence on *injection strength* s in $t \approx 100 t_0$



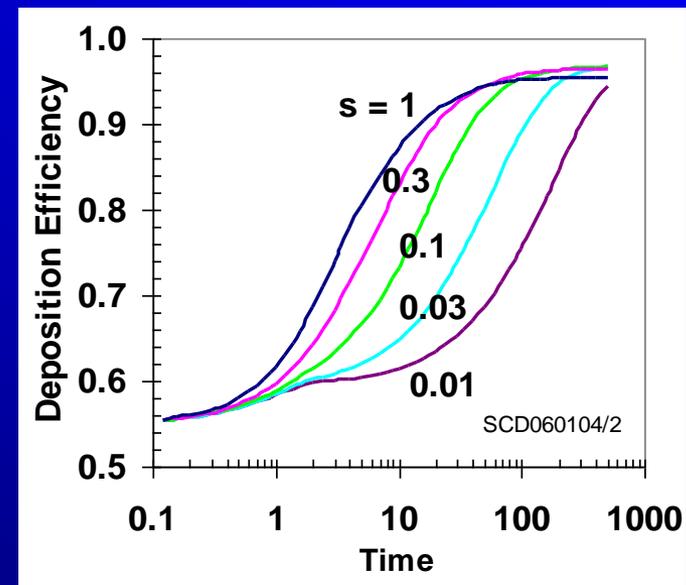
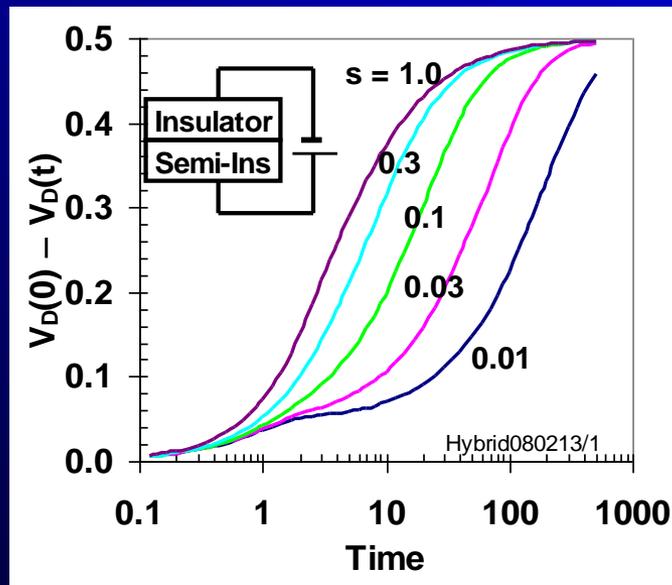
Electrostatic Transfer of Developed Toner

- *Dielectric Relaxation* in receiver
 - Enables efficient transfer without very high V_B
 - increase *transfer efficiency*; depends significantly on *injection strength* s



Transient in Dielectric Relaxation is Most Critical to Performance

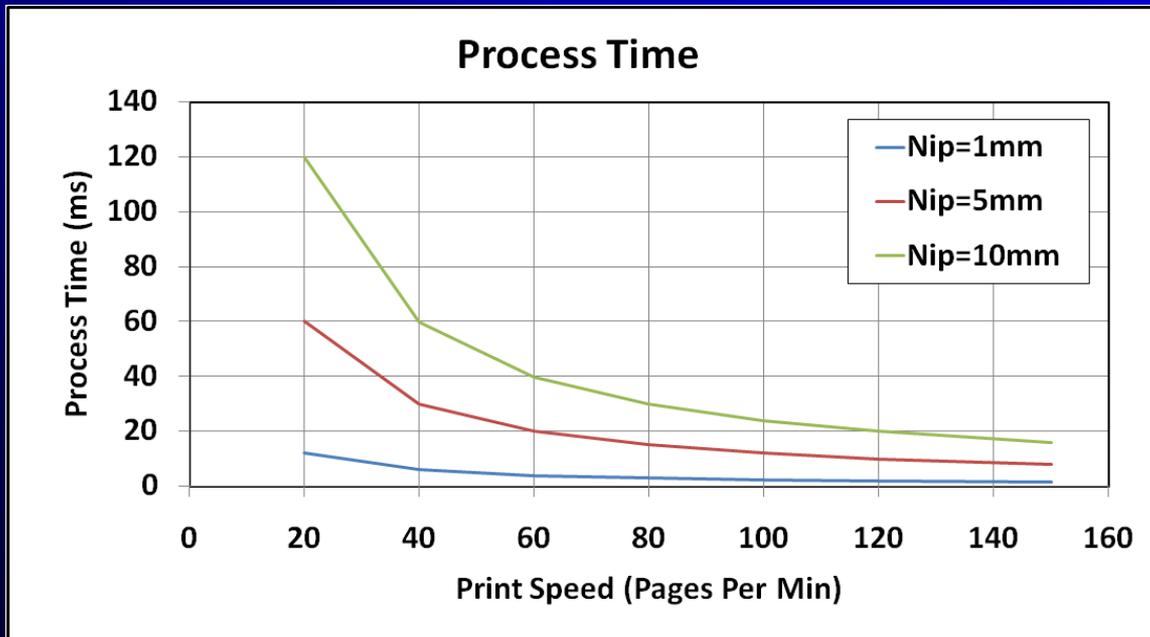
- Close resemblance in analytical results for voltage decay and processes provides strong support for the critical role of dielectric relaxation on EP performance
- Significant effects of s in $t = 10 \sim 100 t_o$, i.e., transient behavior



Relaxation Time vs Process Time

- **Roller or Belt Relaxation Time:**

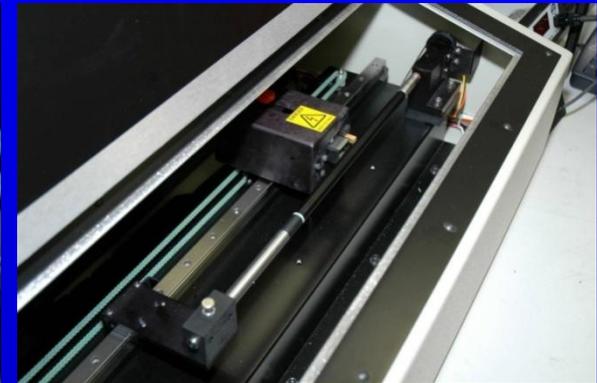
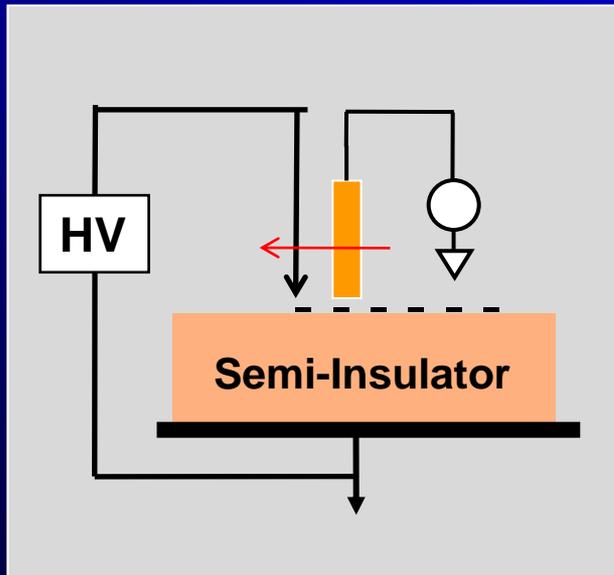
Charge transit time $t_o = L^2/\mu V_B \approx 5 \text{ ms}$; with: $L \approx 50 \text{ } \mu\text{m}$, $\mu \approx 10^{-5} \text{ cm}^2/\text{V-s}$, $V_B \approx 500 \text{ volts}$; full relaxation time is $t_p > 100t_o \approx 0.5 \text{ sec}$ or 500 ms .



- **Therefore must consider transient behavior in characterization; particularly for high speed printing.**

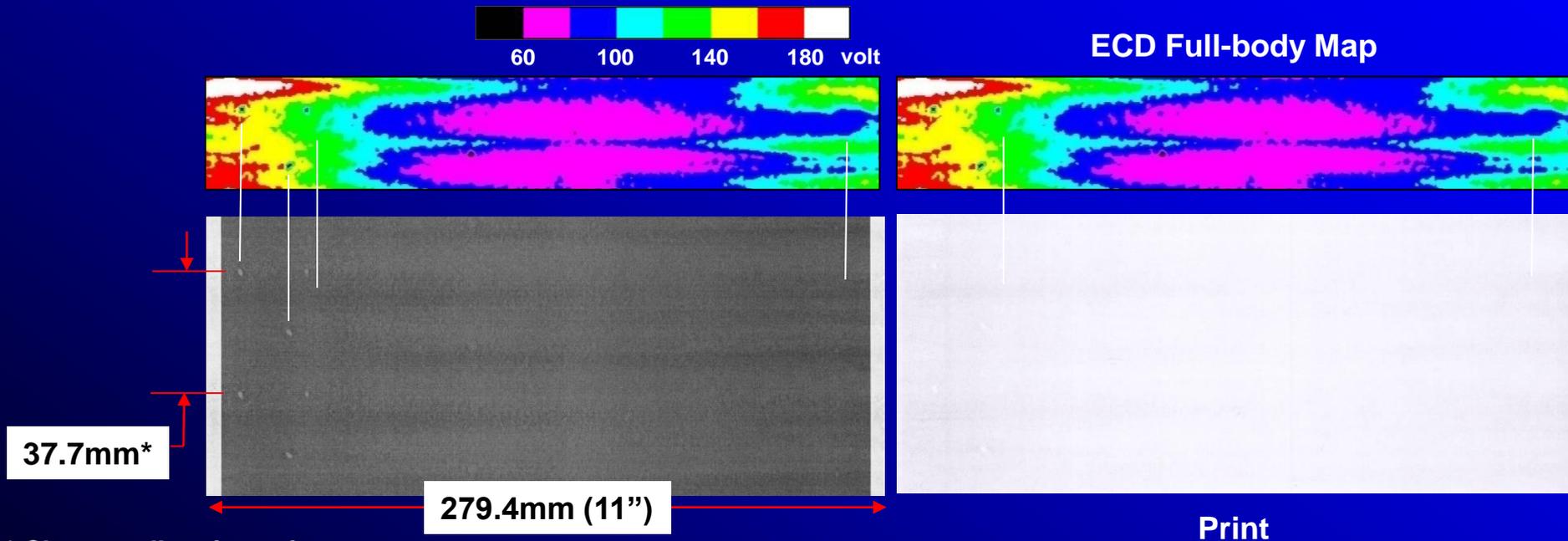
Implementation – the ECD Method

Testing Semi-insulator In Open Circuit



Charge Roller Mapping

- The full-body ECD map shown below for a poor charge roller clearly demonstrates the correlation between V_{ECD} and print quality.
- The non-uniformity in V_{ECD} can be mapped directly to a print density variation map (on a gray page) and a background map (on a white page). Such results clearly demonstrate the efficacy of the ECD method.



* Charge roller circumference



Good Roller

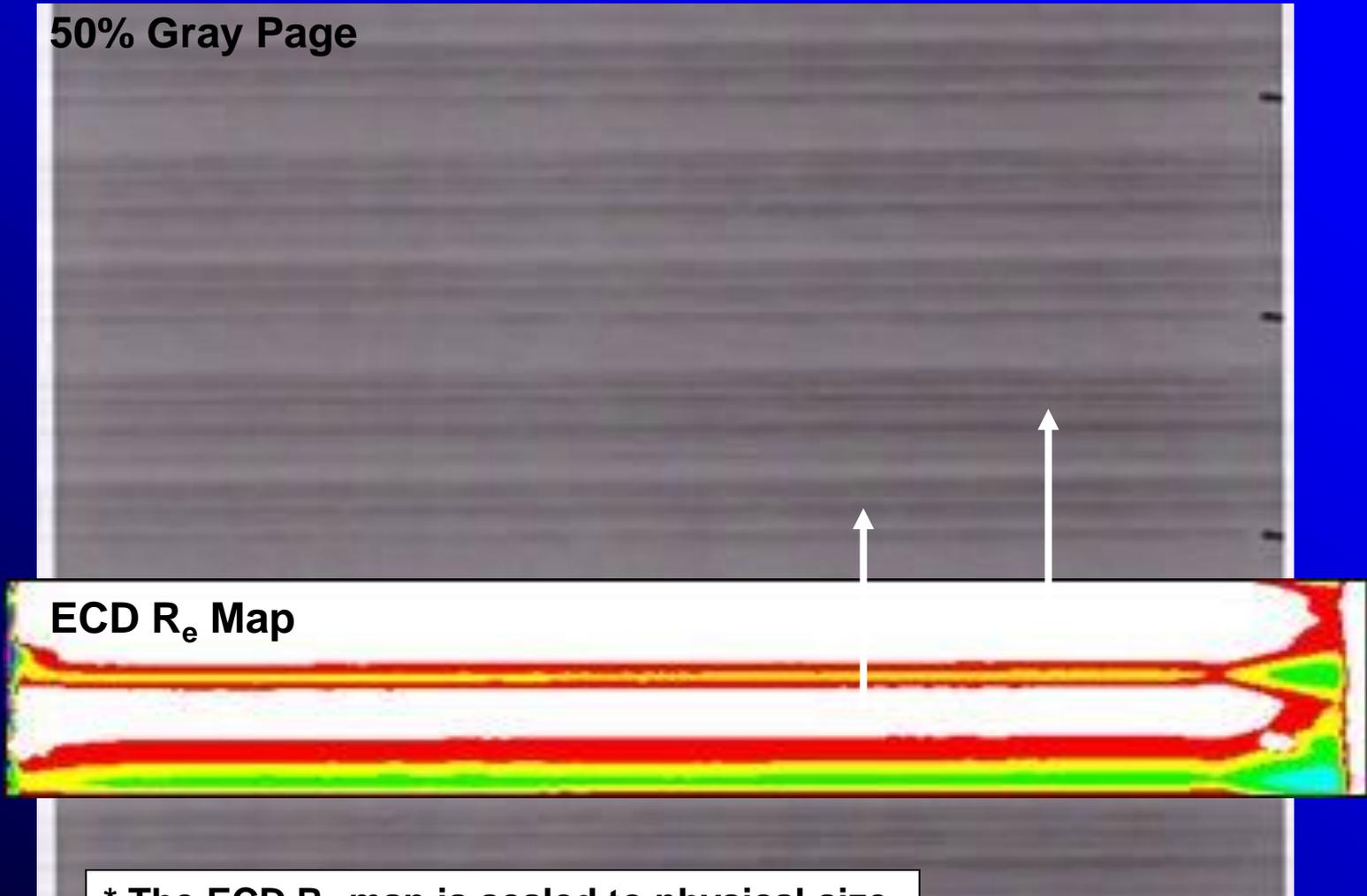
50% Gray Page



* The ECD R_e map is scaled to physical size.

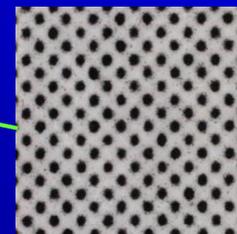
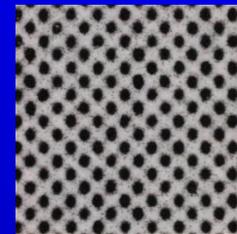
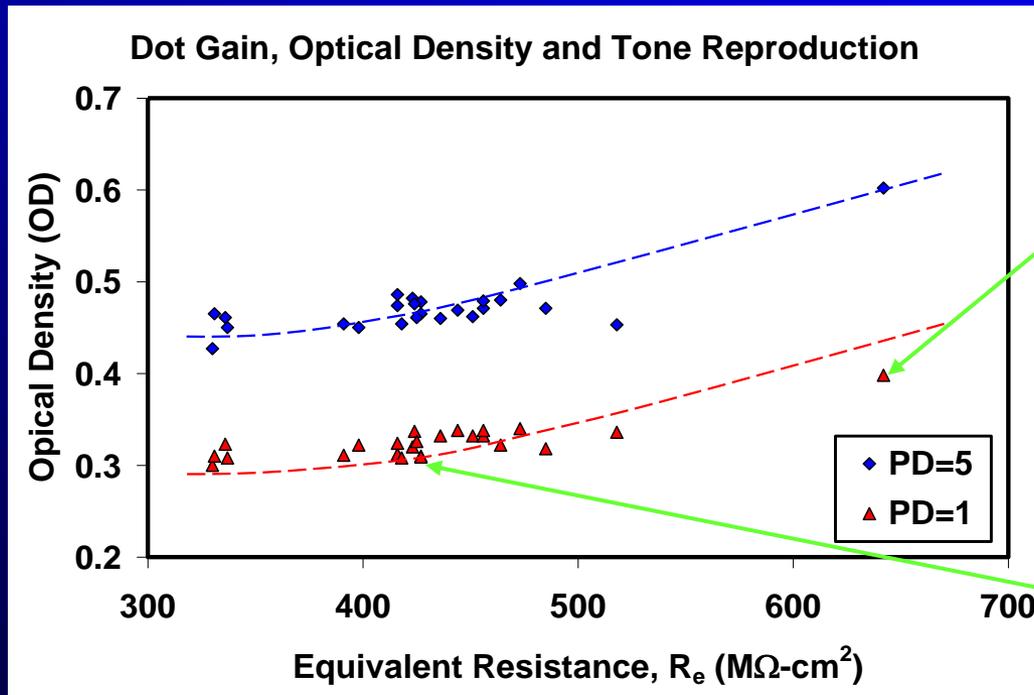
Bad Roller

50% Gray Page

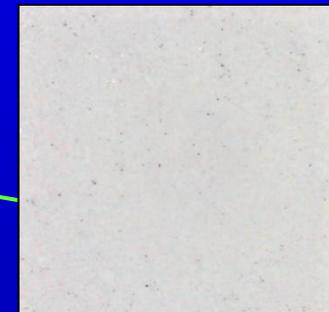
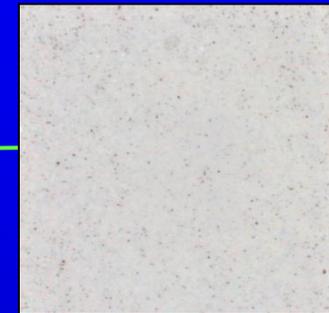
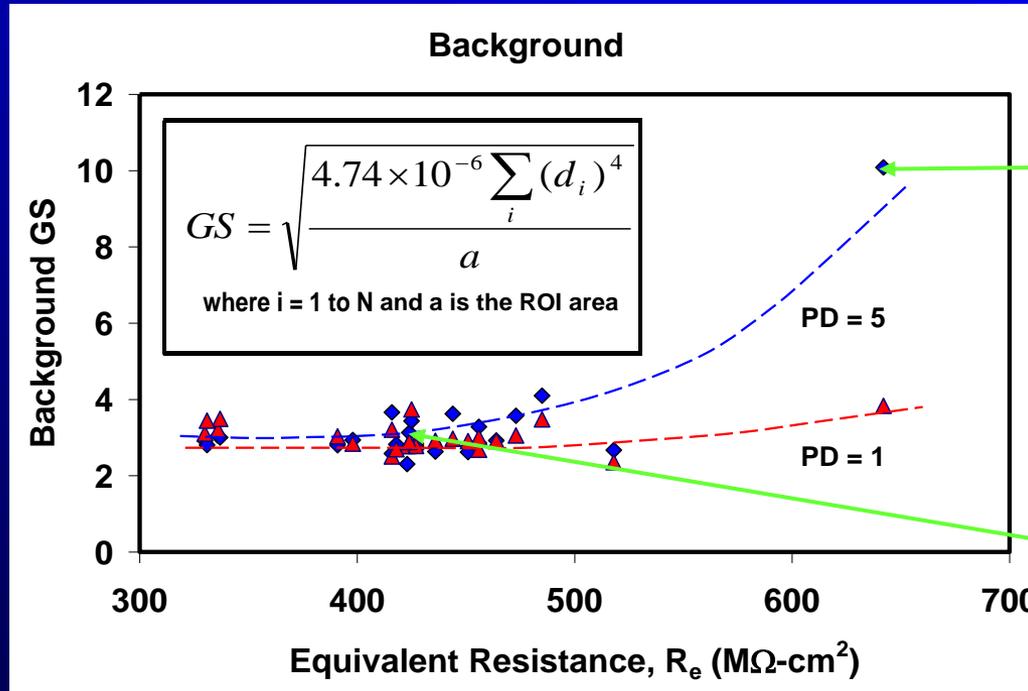


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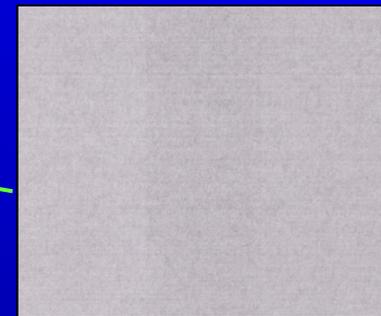
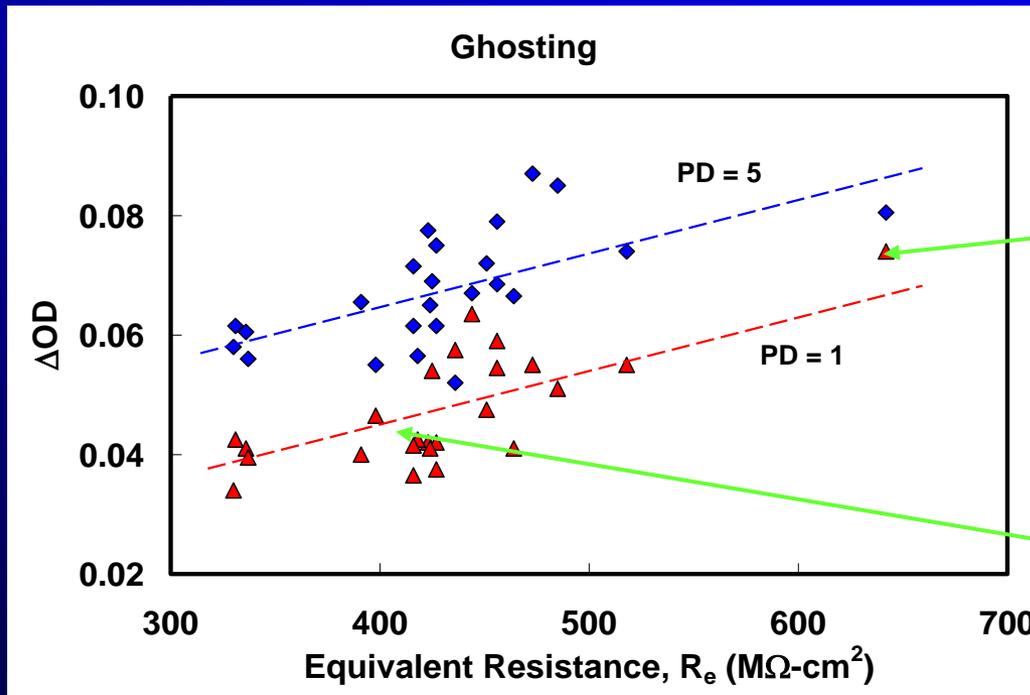
Dot Gain, Optical Density & Tone Reproduction



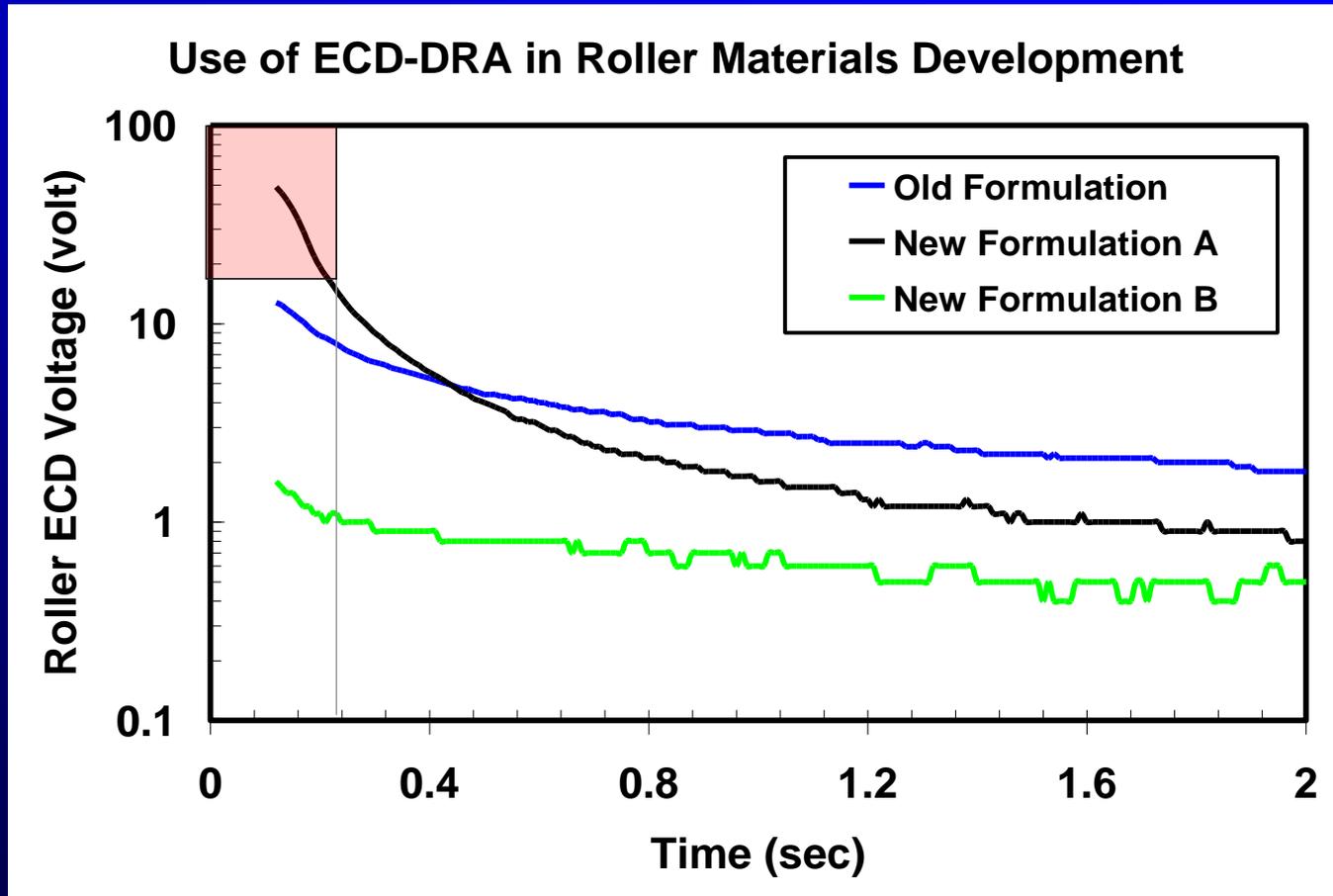
Background



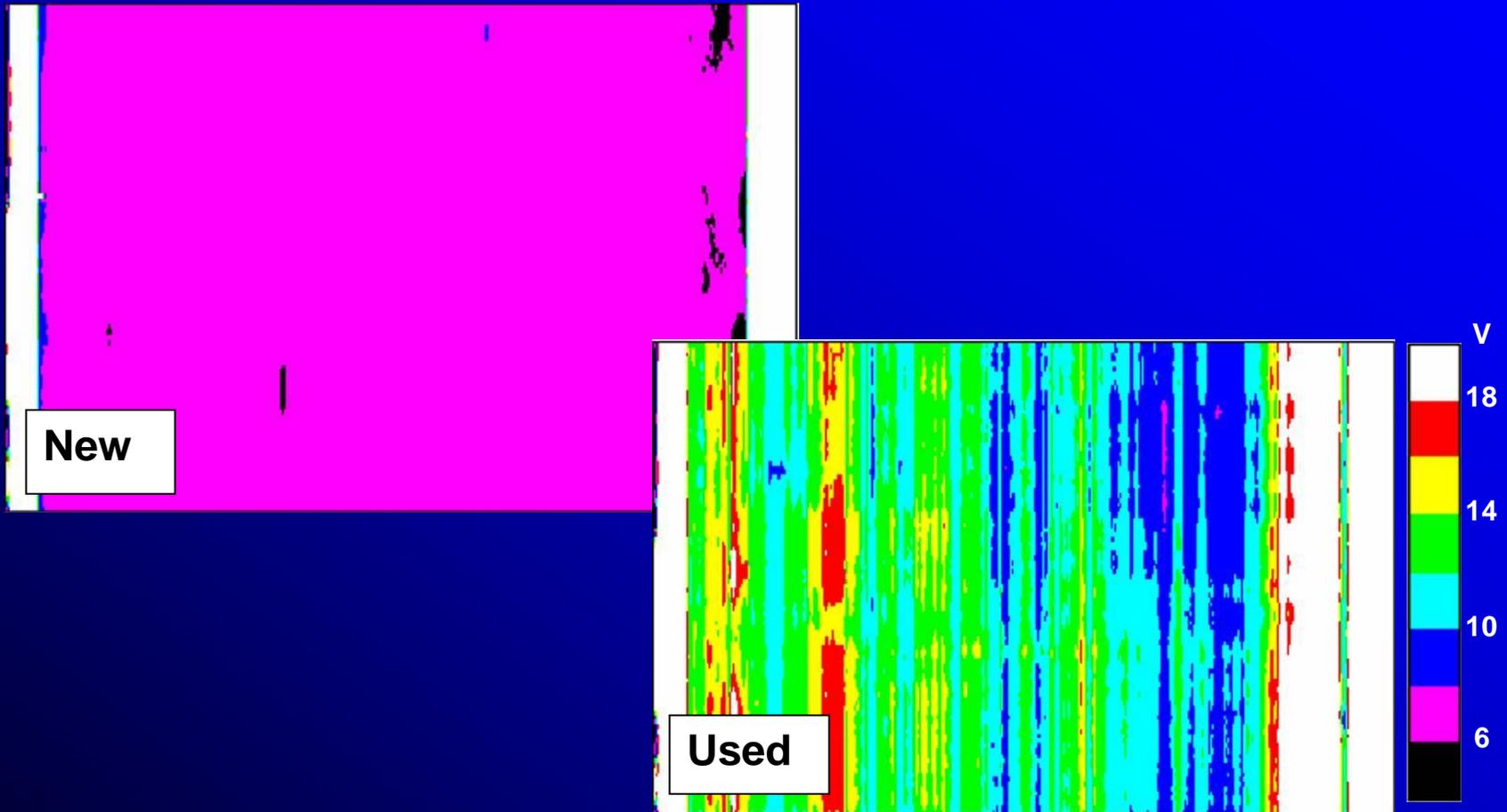
Ghosting



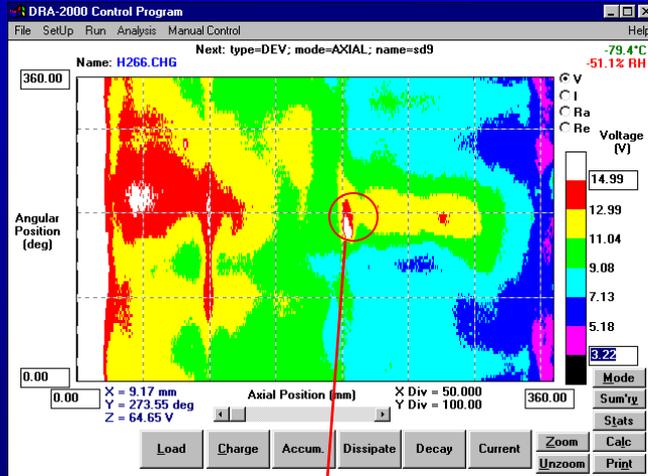
Application Example – Material Formulation



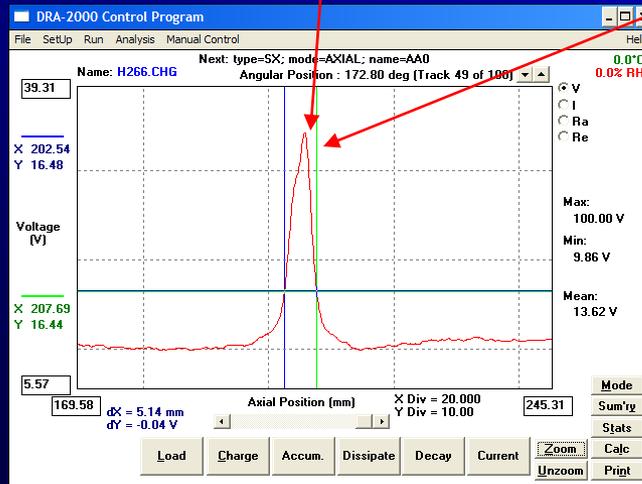
Application Example – Roller Aging



Development Roller



A cut in the roller



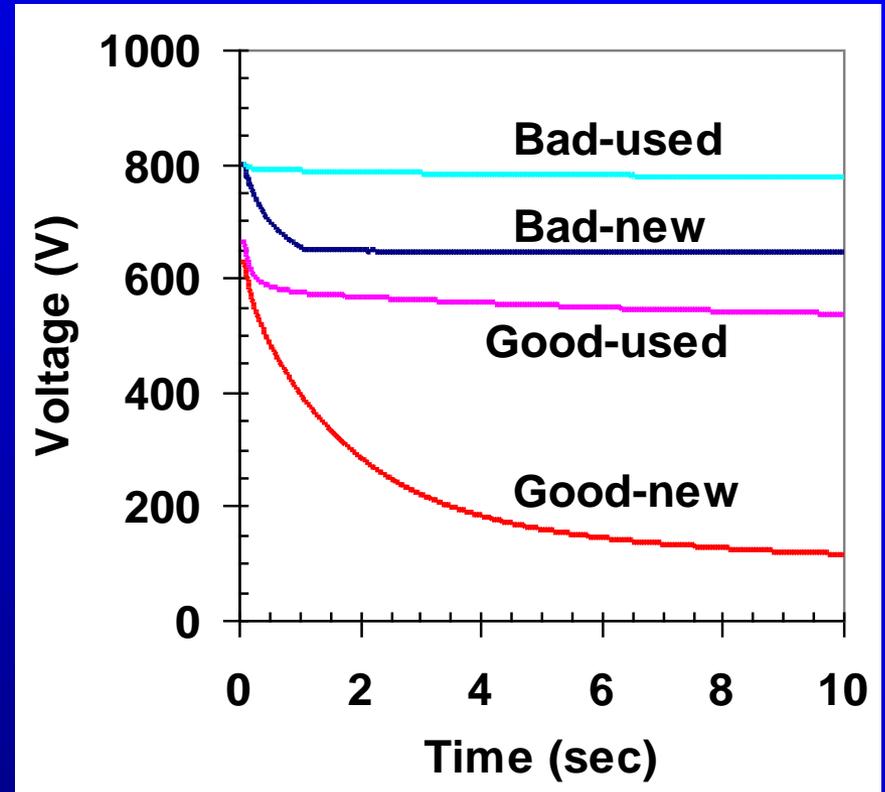
ITB – Failure Analysis

First data points $V(0)$:

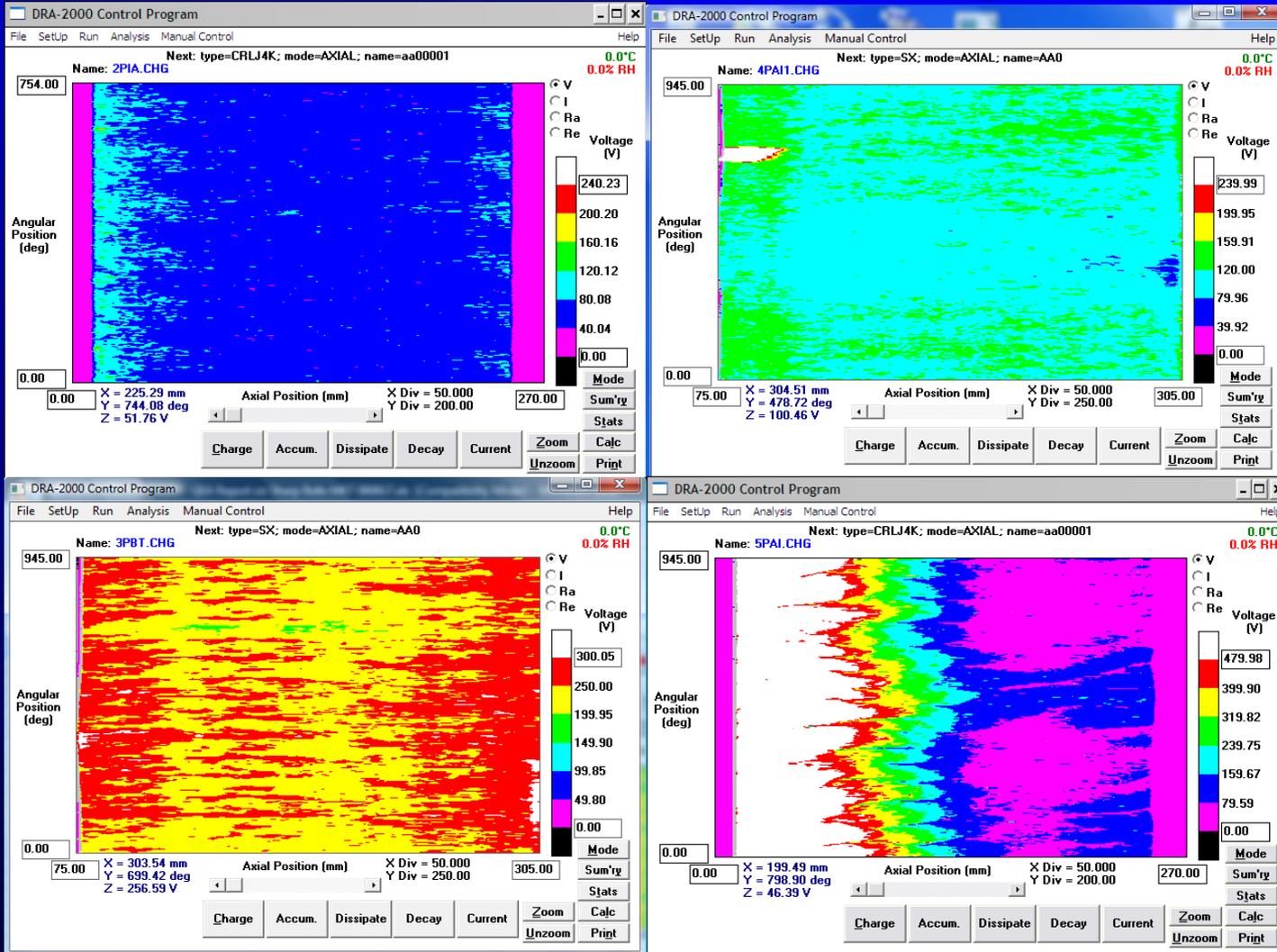
Low for good,
high for bad
same for new and used
→ intrinsic charge

Voltage decay $V(t)$:

Fast for new
Slow for used
→ injected charge



ITB - Benchmarking



Summary

- Performance of EP sub-processes using rollers and belts is controlled by dielectric relaxation (DR) of semi-insulating (SI) layer
- Dielectric relaxation induced by charge injection from bias voltage
- Full relaxation of SI often requires time longer than available in high speed Electrophotography

Conclusions

- **Electrical characterization of rollers and belts should emphasize transient values & spatial variations in DR**
- **Observations of spatial averages, at fully relaxed states are insufficient**
- **Open-circuit voltage measurements, efficiently scanning large area of sample – an extremely valuable tool for R&D, QC and failure analysis**

Thank you for your attention

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See you in the Exhibit Hall

